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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Tadahiro OHMI et al
Title: PLASMA PROCESSING METHOD AND METHOD FOR
MANUFACTURING AN ELECTRONIC DEVICE
Appl. No.: 10/594,895
Filing Date: 11/07/2006
Examiner: Valerie N. Brown
Art Unit: 2829
Confirmation No.: 8302

AMENDMENT AND REPLY UNDER 37 C.F.R. 1.111

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450
Sir:

This communication is responsive to the non-final Office Action dated July 7, 2010, concerning the above-referenced patent application.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this document.

Remarks/Arguments begin on page 4 of this document.

Please amend the application as follows: